L Number	Hits	Search Text	DB	Time stamp
1	2		USPAT	2003/07/08 09:44
	3	"9927325"	EPO; JPO;	2003/07/08 09:44
	i	7721323	DERWENT	2003/07/00 09.44
1_	-	1999-328283.NRAN.	DERWENT	2003/01/10 16:30
	6	9927325.URPN.	USPAT	2003/01/10 16:30
-	_	thermal with membran with sensor	I '	2003/01/10 16:31
-	_		USPAT	
_	157	1	USPAT	2003/01/10 16:33
_	5		USPAT	2003/01/10 17:03
-	· ′ 4	micromechanical near2 membrane near2	USPAT	2003/01/10 17:04
	l	sensor		
-	264		USPAT	2003/01/10 17:05
-	104641	silicon near2 (nitride carbide dioxide)	USPAT	2003/01/13 09:21
-	5612	(thermal or micromechanical) near2 sensor	USPAT	2003/01/12 11:54
-	1389	(428/156).CCLS.	USPAT	2003/01/12 11:54
-	619	(silicon near2 (nitride carbide dioxide))	USPAT	2003/01/12 11:55
		and ((thermal or micromechanical) near2		
		sensor)		
-	35645	428/\$3.\$2.ccls.	USPAT	2003/01/12 11:56
-	2	((silicon near2 (nitride carbide dioxide))	USPAT	2003/01/12 11:56
		and ((thermal or micromechanical) near2		==
	İ	sensor)) and 428/\$3.\$2.ccls.		[
_	1	membrane near2 senor	USPAT	2003/01/13 09:20
-	1543	membrane near2 sensor	USPAT	2003/01/13 09:20
_	104641	!	USPAT	2003/01/13 09:21
_	194	(membrane near2 sensor) and (silicon near2	USPAT	2003/01/13 09:21
	1,74	(mitride carbide dioxide)	33171	2003,01,13 11.11
_	2	(("5834334") or ("5712609")).PN.	USPAT	2003/01/15 10:58
	438	counteracts with deformation	l .	
-	438	Counteracts with deformation	USPAT;	2003/07/07 09:31
	410000	annan	US-PGPUB	2002/07/07 00 03
-	419082	sensor	USPAT;	2003/07/07 09:31
	364634	ailian	US-PGPUB	2002/07/07 00 05
-	364634	silicon	USPAT;	2003/07/07 09:31
	122525	(-111	US-PGPUB	0000/07/07 55 5
-	133535	(silicon near2 nitride) or (silicon near2	USPAT;	2003/07/07 09:31
	400	carbide) or (silicon near2 dioxide)	US-PGPUB	/ _
-	1026078	circuit	USPAT;	2003/07/07 09:31
			US-PGPUB	
-	655	counteract\$5 with deformation	USPAT;	2003/07/07 09:20
			US-PGPUB	
-	17	(counteract\$5 with deformation) and sensor	USPAT;	2003/07/07 09:20
		and silicon	US-PGPUB	į l
-	344561	deform\$5	USPAT;	2003/07/07 09:30
			US-PGPUB	
-	419082	sensor	USPAT;	2003/07/07 09:31
			US-PGPUB	
-	364634	silicon	USPAT;	2003/07/07 09:31
1			US-PGPUB	
] -	133535	(silicon near2 nitride) or (silicon near2	USPAT;	2003/07/07 09:31
		carbide) or (silicon near2 dioxide)	US-PGPUB	
-	205167	deformation	USPAT;	2003/07/07 09:32
			US-PGPUB	
-	8785	(deform\$5 or deformation) and sensor and	USPAT;	2003/07/07 09:50
		silicon	US-PGPUB	======
_	2952	((deform\$5 or deformation) and sensor and	USPAT;	2003/07/07 09:33
	2,52	silicon) and ((silicon near2 nitride) or	US-PGPUB	2005/07/07 09.33
		(silicon near2 carbide) or (silicon near2	30 20208	
		dioxide))	ĺ	
_	31658	(deform\$5 or deformation) with (counteract	USPAT;	2003/07/07 10:43
	71036	or prevent)	USPAT; US-PGPUB	2003/07/07 10:43
1_	211	((deform\$5 or deformation) with		2003/07/07 10:40
-	211		USPAT;	2003/07/07 10:43
		(counteract or prevent)) and sensor and	US-PGPUB	
]		silicon and ((silicon near2 nitride) or		
1		(silicon near2 carbide) or (silicon near2		
	10100	dioxide))		
-	17172	(deform\$5 or deformation) near3	USPAT;	2003/07/07 10:43
		(counteract or prevent)	US-PGPUB	
-	116	((deform\$5 or deformation) near3	USPAT;	2003/07/07 11:35
		(counteract or prevent)) and sensor and	US-PGPUB	
		silicon and ((silicon near2 nitride) or		
		(silicon near2 carbide) or (silicon near2		
		dioxide))		

Page 1

-	0	(((deform\$5 or deformation) near3	USPAT;	2003/07/07 10:44
	ł	(counteract or prevent)) and sensor and	US-PGPUB	1
		silicon and ((silicon near2 nitride) or		
		(silicon near2 carbide) or (silicon near2		
	1	dioxide))) not (((deform\$5 or		
		deformation) with (counteract or prevent))		1
		and sensor and silicon and ((silicon		
	1	near2 nitride) or (silicon near2 carbide)		
		or (silicon near2 dioxide)))		
_	338	((deform\$5 or deformation) near3	USPAT;	2003/07/07 10:45
	330	(counteract or prevent)) and sensor and	US-PGPUB	2003/07/07 10.43
		silicon	US-FGFUB	
	222			0000/07/07 11 45
-	222		USPAT;	2003/07/07 11:45
		(counteract or prevent)) and sensor and	US-PGPUB	1
		silicon) not (((deform\$5 or deformation)		i
		with (counteract or prevent)) and sensor		
		and silicon and ((silicon near2 nitride)		
		or (silicon near2 carbide) or (silicon		İ
		near2 dioxide)))	Ì	
-	0	((0===00:: ::00== :::00==0; or (0===00:: ::00=E	USPAT;	2003/07/07 11:45
İ		carbide) or (silicon near2 dioxide)) and	US-PGPUB	
		5259247.pn.		
-	1	nitride and 5259247.pn.	USPAT;	2003/07/07 12:56
	_	•	US-PGPUB	=====================================
-	7	5259247.URPN.	USPAT	2003/07/07 11:46
_	6	000001770112171	USPAT	2003/07/07 11:47
1		"4719538" "4741214" "4951510").PN.	OULAI	2003/07/07 11:47
_	0	thickness and 5259247.pn.	IISDATT.	2003/07/07 11:51
	١	chickness and 3239247.ph.	USPAT;	2003/07/07 11:51
	420612	-h-h-1-1-05	US-PGPUB	
-	430613	stabiliz\$5	USPAT;	2003/07/07 12:57
			US-PGPUB	
-	841	(deform\$5 or deformation) and stabiliz\$5	USPAT;	2003/07/07 12:57
		and sensor and ((silicon near2 nitride)	US-PGPUB	
1		or (silicon near2 carbide) or (silicon		
		near2 dioxide))		
-	841	(deform\$5 or deformation) and stabiliz\$5	USPAT;	2003/07/07 13:09
		and sensor and ((silicon near2 nitride)	US-PGPUB	
		or (silicon near2 carbide) or (silicon		
		near2 dioxide)) and silicon		
_	39		USPAT;	2003/07/07 13:01
		stabiliz\$5) and sensor and ((silicon	US-PGPUB	2003/07/07 13.01
		near2 nitride) or (silicon near2 carbide)	OS IGIOD	
		or (silicon near2 dioxide)) and silicon		
_	115		IICDAM.	0000/07/07 10 01
	1 113	((deform\$5 or deformation) same	USPAT;	2003/07/07 13:01
1	3.0	stabiliz\$5) and sensor and silicon	US-PGPUB	/ /
-	76		USPAT;	2003/07/07 13:06
		stabiliz\$5) and sensor and silicon) not	US-PGPUB	
		(((deform\$5 or deformation) same	1	l i
		stabiliz\$5) and sensor and ((silicon		
		near2 nitride) or (silicon near2 carbide)		
		or (silicon near2 dioxide)) and silicon		
)		
-	219	(361/283.1).CCLS.	USPAT	2003/07/07 13:06
-	70	(deform\$5 or deformation or stabiliz\$5)	USPAT;	2003/07/07 13:15
		and ((361/283.1).CCLS.)	US-PGPUB	
-	76829	pressure with sensor	USPAT;	2003/07/07 13:14
		•	US-PGPUB	-555, 5,, 5, 15.14
-	2174	silicon and ((silicon near2 nitride) or	USPAT;	2003/07/07 13:15
		(silicon near2 carbide) or (silicon near2	US-PGPUB	2003/07/07 13:13
		dioxide)) and thickness and (pressure	US-EGEUB	
		with sensor)		
_	1000			0000 (07 (07 17 17
1 -	1008	(deform\$5 or deformation or stabiliz\$5)	USPAT;	2003/07/07 13:15
		and (silicon and ((silicon near2 nitride)	US-PGPUB	
		or (silicon near2 carbide) or (silicon		
		near2 dioxide)) and thickness and		
		(pressure with sensor))		
-	516		USPAT;	2003/07/07 14:24
		near2 nitride) or (silicon near2 carbide)	US-PGPUB	
		or (silicon near2 dioxide)) and thickness		
		and (pressure with sensor))		1
	1	4975390.pn. and (thickness or thick)	USPAT;	2003/07/07 14:25
			US-PGPUB	
		L		L